P27165.A07.doc

Application No. 10/707,842

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): H. S. YANG, et al.

Group Art Unit: 2812

Appln. No. : 10/707,842

Examiner: W. L. Lindsay Jr.

Filed

: January 16, 2004

For

: METHOD AND APPARATUS TO INCREASE STRAIN EFFECT IN A

TRANSISTOR CHANNEL

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
U.S. Patent and Trademark Office
Customer Service Window, Mail Stop Amendment
Randolph Building
401 Dulany Street
Alexandria, VA 22314
Sir:

In accordance with the duty of disclosure under 37 C.F.R. § 1.56, and supplemental to the Information Disclosure Statement filed on August 30, 2005, applicant respectfully brings the following documents, listed on the attached form PTO-1449, to the attention of the Examiner in charge of the above-identified application.

Further to the U.S. Patent and Trademark Office's decision to waive the requirement under 37 C.F.R. § 1.98 (a)(2)(i), copies of the U.S. patents and U.S. published patent applications are not enclosed herewith. However, if any copies are needed, the Examiner is respectfully requested to contact the undersigned. Copies of non-US patent documents as well as the documents listed in the "Other Documents" section of the attached PTO-1449 are enclosed.

Applicants respectfully request that the Examiner consider the materials cited and indicate such consideration by appropriately initialing the enclosed PTO-1449 Form and including a copy of the initialed form in the next official communication.

Applicants note that this Information Disclosure Statement is being after receipt of a first action on the merits from the U.S. Patent and Trademark Office. Accordingly, please charge the required fee of \$180.00 to IBM Deposit Account No. 09-0458 (Fishkill).

Should the US Patent & Trademark Office conclude that other fees are required, authorization is hereby given to charge to IBM Deposit Account No. 09-0458 (Fishkill) any fee necessary to ensure consideration of these materials.

Should there be any questions concerning this application, the Examiner is invited to contact the undersigned at the below listed telephone number.

Respectfully submitted, H. S. YANG, et al.

Andrew M. Calderon Reg. No. 38,093

May 15, 2006 GREENBLUM & BERNSTEIN, P.L.C. 1950 Roland Clarke Place Reston, VA 20191 (703) 716-1191 P27165.P08.doc Sheet 1 of 2

FORM PTO-1449		U.S. Department of Commerce Patent and Trademark Office			et No. 238		Application No. 10/707,842		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Applicant Haining S.YANG, et al					
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FORM PTO-1449		U.S. Department of Commerce Patent and Trademark Office			Arty. Docket No. FIS920030238			Application No. 10/707,842			
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